

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masaharu Nagai et al. Art Unit : 1756
Serial No. : 10/694,986 Examiner : Daborah Chacko Davis
Filed : October 29, 2003 Conf. No. : 5334
Title : METHOD FOR REMOVING RESIST PATTERN AND METHOD FOR
MANUFACTURING SEMICONDUCTOR DEVICE

MAIL STOP AF

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF MAY 11, 2006

Please amend the above-identified application as follows:

Amendments to the Claims begin on page 2.

Remarks begin on page 7.